

SVG 8X Track Systems

Smart Solutions for the Semiconductor Industry



Coat – Developer – Scrubber

The **SVG 8X systems** have been used in production since the early 1980s. They have been proven to be a true “work horse”. The process modules are easily removed for troubleshooting or preventive maintenance. System cabinets can be built large enough to make room for future modules.

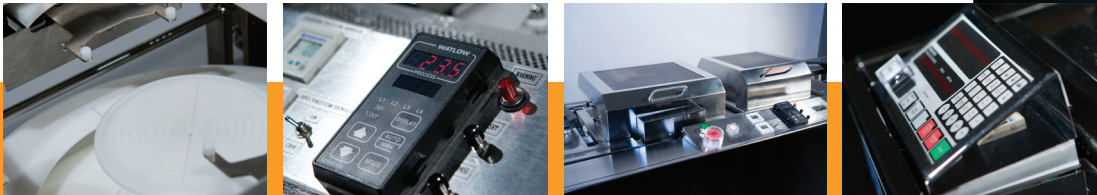
C&D remanufactures, refurbishes, and rebuilds all 8X SVG linear track systems. C&D can refurbish or rebuild track systems to SVG original specifications or reconfigure existing tracks with C&D’s innovative upgrades.



The SVG 86X belt transfer system works well for square or rectangular substrates while the SVG 88X transfer arms provide minimal contact with the backside of the wafer. SVG 86X can run 2” – 6 substrates and the SVG 88X can run 2” – 8” substrates.

SYSTEM FEATURES

- Clean dispense line tips
- Dual size bridging without hardware changeover on 88X
- Recipe Master
- Upgraded ATS arms for repeatability
- Low Turbulence Catch Cup
- 88X systems for 2” – 8” wafers
- Square substrates on 86X systems
- CE Mark
- High performance motors for improved uniformity and reliability
- Sub micron capability
- Digital Vacuum Switches
- Flood Expose
- AutoCAD layout drawings



Reliable and Cost Effective

SVG Tracks consistently operate at 95% uptime. Their proven design and ease of maintenance keeps the cost of ownership very low. For greater than 20 years, this platform continues for use at Universities, R&D companies, and small and large wafer Fabs alike.



SEMICONDUCTOR
SERVICES, INC.

Unique and Innovative Upgrades Driven by Customers

Our 8X track systems are designed and built with innovative and useful upgrades to improve overall performance while at the same time maintaining them as a low-cost alternative. Our engineering team will work closely with you to determine which system configuration best suits your needs.

The C&D Low Turbulence catch cup is designed to greatly reduce the exhaust flow requirement by up to 60% thereby delaying resist drying and virtually eliminating the chance of particulate generation in the Cup. The upper section of the Cup is specific to each wafer size which assures the exhaust flow will be optimized for a given wafer size.

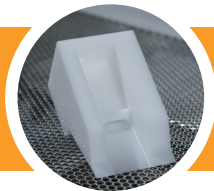
The coat modules can be set up to run four different dispense types plus top and bottom edge bead removal. These dispenses can be set up with small diameter dispense lines for low viscosity material or larger diameter lines for high viscosity.

C&D has increased the repeatability of the 8800 transfer arms by installing an electronic clutch/brake to consistently stop the arm at the same location. Users no longer have to re-adjust the arms on a regular basis and there is no longer a need for particulate generating centering devices on the hot and chill plates.

SVG 8X Track Systems - Features:

DUAL CHAMBER DUNKER

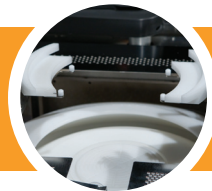
Clean Dispense Tips



C&D has developed a dual chamber dunker, one chamber for solvent and the other for pre dispensing. This innovative dual chamber dunker allows the dispense nozzles to be kept in a solvent rich environment during the idle state keeping the tips clean. This feature has been proven to significantly reduce the need for tip cleaning. By modifying the EPROM, the solvent portion of the dunker is automatically filled from the EBR canister.

DUAL SIZE

Increase OEE



Running two different wafers sizes? C&D continues to lead the pack with innovative solutions. Dual wafer size bridging allows you to run two different wafer sizes without changing hardware. Customers no longer lose valuable production time changing size kits and making the necessary adjustments to release the tool back into production. This dual size bridging feature reduces the cost of ownership while increasing the overall equipment efficiency.

RECIPE MASTER

Data Collection



C&D's powerful Recipe Master software provides capabilities never before seen on the SVG track systems. The Recipe Master logs errors as well as process parameters to assist in troubleshooting process and equipment issues. With Recipe Master you can manually exercise various modules for troubleshooting and performing preventive maintenance. Recipe Master has the capability of password protection to prevent unauthorized access to programs. The Recipe Master software has proven to substantially reduce programming errors. The Recipe Master has, as an option, the capability of communicating with pump controllers. This feature allows users to embed pump programs into the Recipe Master process recipes and thereby using only the amount of resist needed for a particular process.

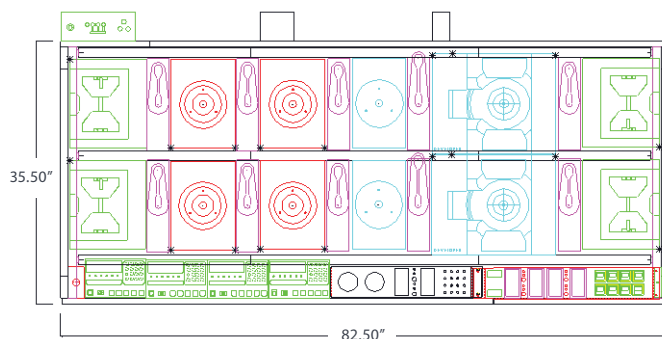


Figure 1

System depicts a two track developer. System dimensions vary depending upon configuration.